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ICS 31.070
CCS L15

SJ

INDUSTRY STANDARD OF THE PEOPLE'S REPUBLIC OF CHINA

SJ 21262-2018

Technical requirements for on-chip testing of MEMS inertial device chips

MEMS 惯性器件芯片在片测试技术要求

(English Translation)

Implemented on: May 1, 2018

Issued by: Ministry of Industry and Information Technology

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https://chinastandards.org/standards/sj-21262-2018

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1 Foreword

SJ 21262-2018 is issued by Ministry of Industry and Information Technology.

The SJ prefix, without a suffix, marks a mandatory standard: within its scope, compliance is required.

The document runs to 8 pages in English translation.

2 Scope Preview

SJ 21262-2018 falls under ICS 31.070, in the field of electronics.

This catalogue holds 133 other SJ standards in that field.

In this catalogue, SJ standards carry edition years from 1965 to 2021.

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3 About this standard

Sector: Electronics Industry Standard

Issued by: Ministry of Industry and Information Technology

English translation: about 8 pages (approximate)

Chinese original: about 12,189 characters

4 Related standards

Standards on related subjects:

GB/Z 40842-2021 - General technical requirenments for electrolarynx

SJ/T 10410-2016 - Permanent ferrite materials

SJ/T 11633-2016 - Supporting high-voltage bus capacitors selective specifications for electric vehicle motor controller

SJ 21264-2018 - MEMS acceleration sensor test method

SJ 21263-2018 - Technical requirements for calibration of MEMS acceleration sensor parameters

SJ 21261-2018 - MEMS inertial device structural design requirements

5 Classification and status

International classification (ICS): 31.070

Chinese Standard Classification (CCS): L 15

Prefix SJ: mandatory standard.

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